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Attorney Docket No.: 0553-0152.02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Shunpei YAMAZAKI et al.
Serial No.: 10/684,936
Filed: October 14, 2003
For: Semiconductor Device And Method
Of Fabricating The Same
Examiner: Thien F. Tran
Art Unit: 2811

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Shannon Wallace

Name of applicant, assignee, or Registered Rep.
Shannon Wallace 7/11/05

Signature Date

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 23313-1450

RESPONSE B (AFTER FINAL)

Applicants have the following response to the Final Rejection of April 5, 2005, a one month extension of time being submitted herewith. Applicants will address each of the Examiner's rejections in the order in which they appear in the Final Rejection.

Claim Rejections - 35 USC §112

In the Final Rejection, the Examiner rejects Claims 81-85 under 35 USC §112, first paragraph, as failing to comply with the written description requirement. This rejection is respectfully traversed.

In particular, the Examiner contends that the "recitation of an electrode through the first silicon nitride oxide film and the second silicon nitride oxide film sets forth a structure not supported